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Sheet 1 of 1

Form FTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. M122-2375		SERIAL NO. 10/635,715	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Winston G. Scott			
				FILING DATE August 5, 2003		GROUP Unknown	
U.S. PATENT DOCUMENTS							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date if Appropriate
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
	AL						
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation
							Yes No
	AM						
	AN						
	AO						
	AP						
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
AS	AR	Wolf, S., "Silicon Processing for the VLSI Era", Vol. 1: Process Technology, 1986 Lattice Press, pp. 434-437.					
	AS						
	AT						
EXAMINER <i>John A. [Signature]</i>				DATE CONSIDERED <i>03/17/05</i>			
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							

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Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-2375		PRIORITY SERIAL NO. 09/876,722	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Winston G. Scott		PRIORITY FILING DATE 6/6/01	
						PRIORITY GROUP 2812	

U.S. PATENT DOCUMENTS							
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
NB	AA	6,033,952	03/00	Yasumura et al.	—	—	
	AB	6,124,168	9/2000	Ong	—	—	
	AC	5,668,705	11/97	Bergemont	—	—	
	AD	5,866,448	2/99	Pradeep et al.	—	—	
	AE	5,858,847	1/99	Zhou et al.	—	—	
	AF						
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FOREIGN PATENT DOCUMENTS							
Document Number	Date	Country	Class	Subclass	Translation		
					Yes	No	
AM							
AN							
AO							
AP							

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)			
NB	AR		Watanabe, H. et al., "Novel 0.44 μ m ² Ti-Salicide STI Cell Technology for High-Density NOR Flash Memories and High Performance Embedded Application", IEEE 1998, pp. 36.2.1 - 36.2.4.
NB	AS		Wolf, S., "Silicon Processing for the VLSI Era", Vol. 2, pp. 632-635.
NB	AT		MITSUBISHI ELECTRIC WEBSITE: Reprinted from website http://www.mitsubishielectric.com/tech/showcase/ts8.php on 3/29/2001: "8. Production Line Application of a Fine Hole Pattern-Formation Technology for Semiconductors", on 3/29/2001, 4 pgs.

EXAMINER <i>Richard A. M.</i>	DATE CONSIDERED 03/17/05
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LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Winston G. Scott		
				PRIORITY FILING DATE 6/6/01	PRIORITY GROUP 2812	
U.S. PATENT DOCUMENTS						
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA					
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FOREIGN PATENT DOCUMENTS						
	Document Number	Date	Country	Class	Subclass	Translation
						Yes No
	AM					
	AN					
	AO					
	AP					
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)						
AR		CAHNER'S SEMICONDUCTOR INTERNATIONAL WEBSITE: Reprinted from http://www.semiconductor.net/semiconductor/issues/1999/sep99/docs/feature1.asp on 3/29/2001: "Resists Join the Sub-λ Revolution", 9 pgs.				
AS		CAHNER'S SEMICONDUCTOR INTERNATIONAL WEBSITE: Reprinted from http://www.semiconductor.net/semiconductor/issues/1999/aug99/docs/lithography.asp on 3/29/2001: "Paths to Smaller Features", 1 pg.				
AT						
EXAMINER		DATE CONSIDERED				
Richard A. Z...		03/17/05				
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